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PATENT
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October 22, 2002
Date

Ayesha S. Wilks

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Vishnu K. Agarwal

Attorney Docket No.: 501082.16 (98-0616.15)

Serial No. : 09/652,580

Group Art Unit : 2825

Filed : August 31, 2000

Examiner : Caridad M. Everhart

Title : DEVICE AND METHOD FOR PROTECTING AGAINST OXIDATION OF A CONDUCTIVE LAYER IN SAID DEVICE

Box Non-Fee Amendment
Commissioner of Patents
Washington, DC 20231

AMENDMENT

Sir:

Please amend the above-captioned patent application as follows:

In the Specification:

Please replace the paragraph beginning at page 8, line 4, with the following rewritten paragraph:

--Still other gases include diborane (B_2H_6); phosphine (PH_3); and carbon-silicon compounds such as methylsilane (CH_3SiH_3) and hexamethyldisilane ($(CH_3)_3Si-Si(CH_3)_3$); and hexamethyldisilazane (HMDS). Additional alternate embodiments of the current invention use hydrazine (N_2H_4), monomethylhydrazine, carbon tetrafluoride (CF_4), CHF_3 , HCl , and boron trichloride (BCl_3), which are also useful in passivating dielectrics, as addressed in copending application 09/114,847, now issued as U.S. Patent No. 6,201,276 B1. Also included are mixtures of any of the gases or types of gases described above. Exemplary non-plasma process parameters using these other gases include a flow rate of about 2 sccm to about 400 sccm for

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